# TRADEMARK ASSIGNMENT COVER SHEET

Electronic Version v1.1 Stylesheet Version v1.2

ETAS ID: TM458760

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	Termination and Release of Trademark and Patent Security Agreement recorded at Reel 4032/Frame 0218

# **CONVEYING PARTY DATA**

Name	Formerly	Execution Date	Entity Type
BHC Interim Funding II, L.P.		01/16/2018	Limited Partnership: DELAWARE

## **RECEIVING PARTY DATA**

Name:	Akrion Systems LLC
Street Address:	6330 Hedgewood Drive, Suite 150
City:	Allentown
State/Country:	PENNSYLVANIA
Postal Code:	18106
Entity Type:	Limited Liability Company: DELAWARE

# **PROPERTY NUMBERS Total: 6**

Property Type	Number	Word Mark
Registration Number:	2993100	LUCID2
Registration Number:	2295797	GOLDFINGER
Registration Number:	2040148	VERTEQ
Registration Number:	2691082	AKRION
Registration Number:	1598327	SUBMICRON
Registration Number:	1574491	SUNBURST

# CORRESPONDENCE DATA

Fax Number: 9494754754

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

Phone: 949-451-3800

skann@gibsondunn.com Email:

Stephanie Kann **Correspondent Name:** 

Address Line 1: 3161 Michelson Drive

Gibson, Dunn & Crutcher LLP Address Line 2: Address Line 4: Irvine, CALIFORNIA 92612

ATTORNEY DOCKET NUMBER:	12833-00001
NAME OF SUBMITTER:	Stephanie Kann

SIGNATURE:	/stephanie kann/
DATE SIGNED:	01/19/2018
Total Attachments: 8	
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# TERMINATION AND RELEASE OF TRADEMARK AND PATENT SECURITY AGREEMENT

THIS TERMINATION AND RELEASE OF TRADEMARK AND PATENT SECURITY AGREEMENT (this "Termination"), is dated as of January 16, 2018, and made by BHC INTERIM FUNDING II, L.P. (the "Grantee"), to AKRION SYSTEMS LLC, a Delaware limited liability company (the "Grantor").

WHEREAS, pursuant to that certain (i) Term Loan and Security Agreement, dated as of June 16, 2009 (as amended, restated or otherwise modified through the date hereof, the "Security Agreement"); and (ii) Trademark and Patent Security Agreement, dated as of June 16, 2009 (as amended, restated or otherwise modified through the date hereof, the "Trademark and Patent Security Agreement"), made by Grantor in favor of Grantee, a security interest was granted by the Grantor to Grantee in certain collateral, including the Trademarks and Patents (as hereinafter defined);

WHEREAS, the Trademark and Patent Security Agreement was recorded with the trademark division of the United States Patent and Trademark Office on July 27, 2009 at Reel 4032, Frame 0218, and with the patent division of the United States Patent and Trademark Office on September 14, 2009 at Reel 23220, Frame 0423; and

WHEREAS, Grantee now desires to terminate and release the Security Agreement and Trademark and Patent Security Agreement;

NOW, THEREFORE, for good and valuable consideration, the receipt and adequacy of which are hereby acknowledged, and upon the terms set forth in this Termination, Grantee hereby states as follows:

- 1. <u>Definitions</u>. The terms "Trademarks" and "Patents" as used herein, shall mean all of the Grantor's right, title and interest of every kind and nature as of the date hereof in the Trademarks and Patents listed on <u>Schedule A</u> hereto.
- 2. <u>Release of Security Interest</u>. Grantee does hereby terminate, release and discharge the entirety of any and all liens or security interests that it may have in, and all claims, whether presently existing or hereafter acquired or created, pursuant to the Security Agreement and Trademark and Patent Security Agreement, in the Trademarks and Patents and reassigns to the person or persons legally entitled thereto all right, title and interest of Grantee in the Trademarks and Patents.

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IN WITNESS WHEREOF, the Grantee has caused this Termination to be executed by its duly authorized officer as of the date first written above.

# BHC INTERIM FUNDING II, L.P.

By: BHC Interim Funding Management, L.L.C. Its: General Partner

By: BHC Investors II, L.L.C.,

Its: Managing Member-

Name: Deane M. Driscoll

Title: Manager

[Signature Page to Second Termination and Release]

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# **SCHEDULE A**

See attached.

# TRADEMARKS

		***************************************	,,		
LUCID2	United States of America	78/224,085	11-Mar-2003	2,993,100	06-Sep-2005
GOLDFINGER	United States of America	75/555,468	18-Sep-1998	2,295,797	30-Nov-1999
VERTEQ	United States of America	75/035,442	21-Dec-1995	2,040,148	25-Feb-1997
AKRION	United States of America	78/122,937	19-Apr-2002	2,691,082	25-Peb-2003
SUBMICRON	United States of America	73/817,473	7-Aug-1989	1,598,327	29-May-1990
SUNBURST	United States of America	73/760,371	28-Oct-1988	1,574,491	02-Jan-1990

# PATENTS

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Cales   US	Title	Country	Application	Application Date	Issue Date	Patent Numbe
US   61/034,142   3/5/2008	Accustic Energy System. Method Apparatus for Processing Flat Articles	SO	11/625,556	1/22/2007		
bee US 11/755,619 XJSV2007  CEIVE US 16/25,651 1722/2007  LUS 11/825,651 1722/2007  LUS 11/825,651 1722/2007  LUS 16/87,292 8/10/2007  Be on US 16/37,292 8/10/2007  LUS 16/37,256 7/12/2007  LUS 16/37,256 7/12/2007  LUS 16/37,256 7/12/2007  LUS 16/37,256 7/12/2007  LUS 16/37,256 7/12/2003 6/21/2005  LUS 16/37,256 7/12/2003 6/21/2005  LUS 16/37,256 7/12/2003 6/21/2005  LUS 16/37,255 4/3/2002 7/21/2004  LUS 16/37,683 12/31/1999 11/12/2003  LUS 03/36,768 12/31/1997 9/11/2001  LUS 03/36,7408 7/11/1997  LUS 03/376,408 7/11/1997  LUS 03/376,408 7/11/1997  LUS 03/376,408 7/11/1997  LUS 03/376,340 7/11/1998  LUS 03/35,365 2/26/2002 8/13/2003  LUS 16/35,365 2/26/2002 8/13/2003  LUS 16/35,366 3/3/1997 9/13/2003  LUS 16/35,366 3/3/2002 8/13/2003  LUS 16/32005	Acoustic Generating Device	SS	61/034,142	3/5/2008		
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US   1/837,292   8/10/2007   1/14/2000	Apparatus and Method for Transmitting Energy Through a Non-Reactive Transmitter Bonded to a Transducer and Use of the Smae to Process	S	11/625,651	1/22/2007		
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atus         US         16/091,011         3/4/2602         1/4/2005           trates         US         08/82/5,883         4/2/1997         9/11/2001         10/19/2004           PSubstrates in a Fluid Container         US         09/36/7,683         12/31/1999         11/18/2003           Strates in a Fluid Container         US         08/852,890         5/23/1997         9/21/1999           Strates in a Fluid Container         US         08/875,408         7/31/1997         9/21/1999           d Container         US         08/8761,717         12/6/1996         6/5/2001           US         09/17/1,271         6/22/1999         8/7/2001           US         09/17/1,271         6/22/1998         2/25/2003           US         09/068.618         7/1/1998         2/25/2003           US         09/068.618         7/1/1998         2/25/2003           US         09/068.618         7/1/1998         2/25/2003           US         09/068.618         7/1/1998         2/25/2003           US         09/07/1,430         6/1/2/2002         8/16/2005           US         10/17/1,429         6/1/2/2002         8/16/2005           1/17/2002         8/16/2005         8/12/2005	Chamical Convention Cantral Device	SU	10/117,725	4/5/2002	7/27/2004	6,766,818
essing Substrates         US         08/825,883         4/2/1997         9/1/2004           realing Substrates in a Fluid Container         US         09/869,213         9/72/2001         10/19/2004           Treating Substrates in a Fluid Container         US         09/367,683         12/31/1999         11/18/2003           realiment         US         08/862,890         5/23/1997         9/72/1999           realiment         US         08/875,408         7/31/1997         9/72/1999           res in a Fluid Container         US         08/8761,717         12/6/1996         6/5/2001           res in a Fluid Container         US         08/761,717         12/6/1996         6/5/2001           res in a Fluid Container         US         09/171,271         6/72/1998         8/7/7601           US         09/171,271         6/72/1998         8/7/7601           US         09/171,271         6/72/1998         2/72/1903           in a Process Tank         US         09/058,618         7/7/1998         2/72/1903           ice That Shuts Down Operation in Response         US         08/851,668         5/6/1997         9/15/1998           er System         US         10/053,449         1/17/2002         8/16/7005           er	Cheminal Collectionshop Started and America	US .	10/091,011	3/4/2002	1/4/2005	6,837,944
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Treating Substrates in a Fluid Container   US   08/852,890   5/23/1997   9/21/1999	trates in a Fluid	SU	09/367,683	12/31/1999	11/18/2003	6,647,641
realiment         US         08/875/408         7/3 //1997         5/1 //1999           res in a Fluid Container         US         08/761/717         12/6/1996         6/5/2001           res in a Fluid Container         US         09/171/271         6/22/1999         8/1/2001           res in a Fluid Container         US         09/171/271         6/22/1999         8/1/2001           US         10/085/565         1/26/2002         1/18/2003           In a Process Tank         US         09/068.618         7/1/1998         2/25/2003           ice That Shuts Down Operation in Response         US         09/831,668         5/6/1997         9/15/1998           Rope         US         10/053,449         1/17/2002         3/19/2005           VS         10/171,430         6/12/2002         8/16/2005           er System         US         10/171,426         6/12/2002         8/12/2005           er System         US         10/171,426         6/12/2002         8/12/2005	Fluid Con	S.O.	08/862,890	5/23/1997	9/21/1999	5,954,068
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CS   09/171,271   6/12/1999   8/17/2001	Device for Transing Substrates in a Plusici Container	US	08/761,717	12/6/1996	6/5/2001	6,240,938
10/085/365   10/085/365   1/18/2002   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2003   1/18/2002   1/18/2003   1/	Daving for West Treatment of Substitutes	S	09/171,271	6/22/1999	1007/78	770,407
in a Process Tank US 09/068.6 i 8 7/1/998 2/25/2063 ice That Shuts Down Operation in Response US 08/851,568 5/6/1997 9/15/1998  Rope US 10/053,449 1/17/2002 3/12/2005 er System US 10/171,426 6/12/2002 8/16/2005 its 10/171,426 6/12/2002 8/12/2004	Devise Dans	SC	10/085,565	2/26/2002	1/18/2005	6,843,859
Rope	-41	SUS	8197068	377/13958	2/25/2003	6,523,552
Rospe         US         10/053/449         1/17/2002         3/12/2003           VS         10/171/430         6/12/2002         8/16/2003           er System         US         10/171/426         6/12/2002         8/2/2003           er         US         10/171/426         6/12/2002         8/2/2004	Industrial Robot Safety Device That Shuts Down Operation in Response	SU	08/831,668	5/6/1997	9/15/1998	5,807,408
System         US         10/171/430         6/12/2002         8/16/2005           US         10/171/426         6/12/2002         8/2/2005           11S         10/171/426         6/12/2002         6/29/2004	to Variation in Tension of a Rope	100	פאא נשתות:	1/17/2007	3/29/2005	6,871,657
US 10/171.425 6/12/2002 8/2/2004		700	10/17/430	6/12/2002	8/16/2005	6,928,751
11S 10/71.426 6/12/2002 6/29/2004	Regasonic Cleaner and Cryst System	SO	10/171,429	6/12/2002	8/2/2005	6,923,192
	MERCANNIC CICARRY AND LAYES	SU	10/171,426	6/12/2002	6/29/2004	6,754,980

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Megasonic Cleaner and Dryer	SU	10/864,927	6/10/2002	9/5/2006	7,100,304
Magazonic Cleaner Prohe System with Gasified Fluid	SO	09/906,384	7/16/2001	2/3/2004	6,684,890
Macaconic Cleaner Probe System with Gasified Fluid	SU	10/742,214	12/19/2003	5/23/2006	7,047,989
Megasonic Cleaner Probe System with Gasified Fluid	SU	10/864,929	6/10/2004	1/2/2007	7,156,111
Megasonic Cleaner Prohe System with Gasified Fluid	SU	11/595,029	11/9/2006		
Manageric Cleaner System With Buffered Cavitation Method	SU	10/341,425	1/10/2003	9/12/2006	7,104,268
Merseonic Cleaning System	SU	08,277,792	7/20/1994	4/29/1997	5,625,249
Meraconic Cleaning System	SU	07/791,094	11/12/1991	9/28/1993	5,247,954
Approprie Drohe Brand Attenuator	SU	09/922,509	8/3/2001	1/20/2004	6,679,272
Megasonic Probe Energy Affendator	SU	10/760,596	1/20/2004	5/17/2005	6,892,738
Megasonic Probe Energy Director	SU	10/059,682	1/29/2002	10/30/2007	7,287,537
Megasonic Probe Energy Director	SU	11/873,750	10/17/2007		200
Megasonic Transducer Assembly	SU	08/042,889	4/5/1993	11/22/1994	3,363,960
Megazone System	US	10/117,768	4/5/2002	3/18/2003	6,000,100
Megazone System	US	10/304,583	11/25/2002		0,020,189
Membrane Dryer	SN	10/117/739	4/5/2002		0,842,998
Mornhrane Divier	SD	10/951/009	9/27/2004	8/16/2005	6,928,750
וז ביו מיותוי בין אי	SU	08/275,807	7/15/1994	9/17/1996	5,556,479
Northod and Apparatus for Treating Substrates	SU	09/600,084	6/30/2000	8/19/2003	6,607,604
MICHAEL TO COMMISSION OF THE PROPERTY OF THE P	SU	10/053,364	1/18/2002	7/27/2004	6,767,877
Method and System for Processing a Substrate Using a Composite	SN	60/985,947	11/6/2007		
Method and Systems for Determining Chemical Concentrations and Controlling the Processing of Semiconductor Substrates	SN	09/257,488	2/25/1999	7/17/2001	0,201,840
Method for Cavitation Measurement	SU	61/031,845	2/27/2008		
Method for Part. CMD Advanced Front End of Line Cleaning	SO	12/070,620	2/19/2008		
MODION OF LOSS CHAINS AND ASSESSMENT	SU	09/096,898	6/12/1998	10/26/1999	5,972,123
Nextoen Wet Process Tank	SN	10/117,778	4/5/2002	1/11/2005	6,840,250
Norzel for like in the Megasonic Cleaning of Substrates	SU	11/781,835	7/23/2007		232010
1000 M 400 M 400 M	SD	10/366,054	2/13/2003	11/16/12004	0,616,000
S. Patting Onida Eilers in a Sealed Photochemical Reactor	SU	07/876,043	4/30/1992	8/10/1993	5,234,540
Process for Electing Oxfue China in a Date of Photomasks	SU	10/909,764	8/2/2004	1/30/2007	7,169,253
Process Sequence for Photoresist Stripping and Cleaning of Photomasks	SN	11/649,535	1/4/2007		

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Reciprocating Megasonic Probe	SU	10/140,029	5/6/2002	3/6/2007	7,185,661
Reciprocating Megasonic Probe	SU	11/640,718	12/18/2006		
	SU	08/361,139	12/21/1994	8/12/1997	5,656,097
/	SU	08/908,330	8/7/1997	6/1/1999	5,908,509
	SU	08/908,345	8/7/1997	12/7/1999	5,996,595
	SU	08/910,033	8/11/1997	9/14/1999	5,950,645
	SU	09/694,938	10/23/2000	4/30/2002	6,378,534
Single Chamber Megasonic Energy Center	SN	07/598,909	10/16/1990	9/22/1992	5,148,823
Olific Citation in Sanctife City	SD	07/598,426	10/16/1990	2/25/1992	5,090,432
	SU	07/809,799	12/18/1991	2/15/1994	5,286,657
Spray Jet Cleaning Apparatus and Method	SU	11/745,866	5/8/2007		
Substrate Process Tank with Acoustical Source Transmission and	SO	10/699,042	10/31/2003	10/18/2005	6,955,727
Method of Processing Substrate			6.5000	300001	C55 081 9
Substrate Processing Device	SO	09/308,850	5/24/1999	7/20/2001	0,107,002
System and Method for Drying a Rotating Substrate	US	11/624,445	1/18/2/00/	2000	1
System and Method for Point-of-Use Filtration and Purification of Fluids	SO	10/895,511	7/20/2004	1007/02/71	,,0,11,04,
Used in Substrate Processing	01.1	11/841 427	8/20/2007		
System and Method for Flocessing a Substitute Officing a Cos Survein for Particle Removal	(				
System and Method for Selective Etching a Silicon Nitride During	S	10/585,229	4/20/2007		
System and Method of Cleaning Substrates Using a Subambient Process	SU	11/544,802	10/6/2006		
Solution					
System and Method of Determining the Operating Frequency at Which to	SO	12/059,602	3/31/2008		
power a Transducer	150	11/454 447	6/15/2006		
System and Method of Processing Substrates Using Sonic Energy Having Cavitation Control	ů	11/40/49/44 4			
System for Removal of Photoresist Using Sparger	US	10/052,823	1/17/2002	11/18/2003	910,640,0
System for Removal of Photoresist Using Sparger	SO	10/634,440	8/5/2003	3/8/2005	6,865,856
Transducer Assembly Incorporating a Transmitter Having Through Holes and Method and System for Cleaning a Substrate Utilizing the	SO	11/777,252	7/12/2007		
Same		2000	00001000	1000/11/01	608 805 9
Vapor Drying System and Method	US	100,122,160	2/10/1/2/	112/12/17	5.226.242
Vapor Jet Dryer Apparatus and Method	118	08/774 518	9/30/1996	3/21/2000	6,039,059
	Sil	09/057,182	4/8/1998	10/31/2000	6,140,744
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